Supplementary information

A generic approach for aligning liquid crystals using solution-processed 2D materials on ITO-free surfaces

Gayathri R. Pisharody,^{a,b} Priyabrata Sahoo,^{a,b} Abhishek Kumar Mishra^c, D. S. Shankar Rao,^a H. S. S. Ramakrishna Matte^{a*}, and S. Krishna Prasad^{a*} ^aCentre for Nano and Soft Matter Sciences, Shivanapura, Bengaluru 562162 India ^bManipal Academy of Higher Education (MAHE), Manipal, 576104 India ^cDepartment of Physics, Applied Science Cluster, School of Engineering, University of Petroleum and Energy Studies (UPES), Dehradun, 248007, India **skprasad@cens.res.in*

*matte@cens.res.in

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Compound	Molecular formula	Phase sequence
E7		1%) I (57 °C) N
		5%)
		L6%)
	CN 5CT (8	%)
E44	Structure not known	I (118 °C) N
ZLI-2359	Structure not known	I (70.4 °C) N
РСРВВ		I (124 °C) N
6OCN	C ₆ H ₁₃ O	I (135 °C) N

Table S1: Table showing the molecular structure and transition temperature of the materialsemployed for the study



Figure S1: Schematics of the POM setup to collect the transmitted intensity upon sample rotation in azimuthal direction



Figure S2: *XRD plot of h-BN/AZO substrate. The region marked in green shows the diffraction from the (002) plane of h-BN. The diffraction from other planes corresponding to ZnO is also marked.*



Figure S3: (a) AFM topography image of h-BN nanosheets, (b) line profiles showing the thickness of the various nanosheets.



Figure S4: Energy dispersive X-ray (EDX) spectrum of h-BN/AZO substrate



Figure S5: *Elemental mapping of Zinc, oxygen, aluminium and nitrogen in the h-BN/AZO substrate*



Figure S6: Alignment of E7 in the commercial PI/ITO cell. The director orientation (n) cell is (a) at 45°, and (b) at 0° with respect to the polarizer/analyzer orientation respectively.



Figure S7: Polar plot of transmitted intensity (I_T) vs. azimuthal rotation for E7 in (a) h-BN/ITO cell and (b) PI/ITO cell





Figure S8: Measurement of birefringence intensity variation along two different lengths of the POM image for (a) CVD HOPG, (b) CVD h-BN, (c) CVD MoS₂, (d) CVD HOPG/PVA, (e) CVD WSe₂, and (f) CVD MoSe₂ cell filled with 5CB taken from Ref. 37, Ref. 39 and Ref. 40. Birefringence intensity variation in ITO/h-BN cell filled with (g) ZLI-2359, (h) E44, and (i) E7. (j) Birefringence variation of E7 filled in PI/ITO cell. Insets show the corresponding POM image taken for analysis. The dotted line indicates the path along which the gray value is measured.

Table S2: Mean and standard deviation obtained from the birefringence analysis of the POM images and compared with the literature values

Conducting / underlying layer	Aligning layer	LC used	Mean Gray value	Standard deviation	References
ΙΤΟ	CVD-h-BN	E7	168	9.6	<i>Ref 32</i>
Silicon	CVD-h-BN	5CB	84	35	<i>Ref 40</i>
Silicon	CVD-graphene	5CB	54	27.2	<i>Ref 40</i>
Silicon	CVD-MoS ₂	5CB	110	21.1	<i>Ref 40</i>
Glass	CVD- HOPG/PVA	5CB	51	39	<i>Ref</i> 39
Silicon	CVD MoSe ₂	5CB	53	41.5	<i>Ref</i> 37
Silicon	CVD WSe ₂	5CB	91	28.1	<i>Ref</i> 37
ΙΤΟ	EPD-h-BN	E7	173	5.1	Ref 31
ΙΤΟ	EPD-h-BN	E44	175	8.9	This work
ITO	EPD-h-BN	ZLI-2359	185	2.8	This work
AZO	EPD-h-BN	E7	112	1.4	This work
AZO	EPD-h-BN	E44	124	1.8	This work
AZO	EPD-h-BN	ZLI-2359	107	4.2	This work



Figure S9: Forward and backward dielectric response curves with applied DC bias (-30 V to +30 V) for PI/ITO layer